



PATENT
Attorney Docket No.: 018865-003600US
Client Reference No.: 17732-9953

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Joelle Sharp et al.

Application No.: 09/448,884

Filed: November 24, 1999

For: HYDROGEN ANNEAL FOR
CREATING AN ENHANCED TRENCH
FOR TRENCH MOSFETS

Examiner: David Vu

Art Unit: 2818

SUPPLEMENTAL INFORMATION
DISCLOSURE STATEMENT
UNDER 37 CFR §1.97 and §1.98

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

January 9, 2004

Sir:

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The references cited on attached form PTO/SB/08A and PTO/SB/08B are being called to the attention of the Examiner. Copies of the references are not enclosed.

It is respectfully requested that the cited references be expressly considered during the prosecution of this application, and the references be made of record therein and appear among the "references cited" on any patent to issue therefrom.

As provided for by 37 CFR 1.97(g) and (h), no inference should be made that the information and references cited are prior art merely because they are in this statement and no representation is being made that a search has been conducted or that this statement encompasses all the possible relevant information.

This IDS is being filed before the mailing date of the final Office Action or Notice of Allowance.

CERTIFICATION

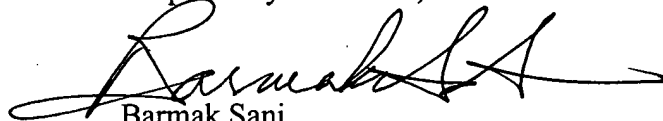
I hereby certify that no item of information contained in the Information Disclosure Statement filed herewith was cited in a communication from a foreign patent office in

a counterpart foreign application, and, to my knowledge after making reasonable inquiry, no item of information contained in this Information Disclosure Statement was known to any individual designated in 37 CFR 1.56(c) more than three months prior to the filing of this Information Disclosure Statement.

Applicant believes that no fee is required for submission of this statement.

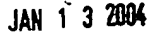
However, if a fee is required, the Commissioner is authorized to deduct such fee from the undersigned's Deposit Account No. 20-1430. Please deduct any additional fees from, or credit any overpayment to, the above-noted Deposit Account.

Respectfully submitted,

A handwritten signature in black ink, appearing to read 'Barmak Sani', with a long horizontal flourish extending to the right.

Barmak Sani
Reg. No. 45,068

TOWNSEND and TOWNSEND and CREW LLP
Two Embarcadero Center, Eighth Floor
San Francisco, California 94111-3834
Tel: 650-326-2400
Fax: 650-326-2422
TYB:tyb



(use as many sheets as necessary)

Sheet 1 of 2

Application Number	09/448,884
Filing Date	November 24, 1999
First Named Inventor	Sharp, Joelle
Art Unit	2818
Examiner Name	David Vu
Attorney Docket Number	018865-003600US

[illegible][illegible]

Date Considered

¹ EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ² Applicant's unique citation designation number (optional). ³ Kind Codes of U.S. Patent Documents at www.uspto.gov or MPEP 901.04. ⁴ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁵ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁶ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁷ Applicant is to place a check mark here if English language Translation is attached.



INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Complete if Known			
		Application Number	09/448,884		
		Filing Date	November 24, 1999		
		First Named Inventor	Sharp, Joelle		
		Art Unit	2818		
		Examiner Name	David Vu		
Sheet	2	of	2	Attorney Docket Number	018865-003600US

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	0005	CHANG et al., "A Highly Manufacturable Corner Rounding Solution for 0.18 μ m Shallow Trench Isolation," IEDM Tech. Digest, pp. 661-664 (1997).	
	0006	NOURI et al., "An Optimized Shallow Trench Isolation for sub-0.18 μ m ASIC Technologies," SPIE Vol. 3506, pp. 156- 166 (September 1998).	
	0007	MATSUDA et al., "Novel Corner Rounding Process for Shallow Trench Isolation utilizing MSTs (Micro-Structure Transformation of Silicon)," IEDM Tech. Digest, pp. 137-140 (December 1998).	
	0008	NANDAKUMAR et al., "Shallow Trench Isolation for advanced ULSI CMOS Technologies," IEDM Tech. Digest, pp. 133-136 (December 1998).	

Examiner Signature		Date Considered	
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* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Applicant's unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.